

Notic of References Cited

Application/Control No.		Applicant(s)/Patent Under Reexamination
09/902,672		FUNABASHI, MICHIMASA
Examiner	Art Unit	
Lex Malsawma	2825	Page 1 of 1

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NON-PATENT DOCUMENTS

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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.